



GP-1731 #2  
SP01-330  
BS  
6-27-02

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Bradley F. Bowden  
Kenneth E. Hrdina

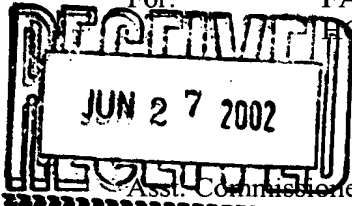
Examiner: To Be Assigned

Serial No: 10/086,238

Group Art Unit: 1731

Filed: February 27, 2002

For: FABRICATION OF INCLUSION FREE  
HOMOGENEOUS GLASSES



INFORMATION DISCLOSURE STATEMENT  
UNDER 37 C.F.R. §§ 1.56, 1.97 - 1.98

Asst. Commissioner of Patents and Trademarks  
Washington, DC 20231

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TC 1700

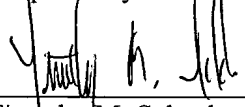
Dear Sir:

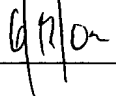
The Examiner's attention is hereby directed to the following reference(s) listed on the attached Form PTO-1449 for consideration in connection with the examination of the above-identified patent application. One copy of the reference(s) is enclosed.

This submission does not represent that a search has been made or that no better art exists and does not constitute an admission that each or all of the enclosed documents constitute "prior art." If it should be determined that any of the submitted documents do not constitute "prior art" under United States law, applicant(s) reserve the right to present to the office the relevant facts and law regarding the appropriate status of such documents.

Applicant(s) further reserve the right to take appropriate action to establish the patentability of the disclosed invention over the enclosed references, should one or more of the references be applied against the claims of the present application.

Respectfully submitted,


  
\_\_\_\_\_  
Timothy M. Schaeberle  
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Date:  \_\_\_\_\_

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to Asst. Commissioner of Patents and Trademarks, Washington, D.C. 20231

on June 14, 2002  
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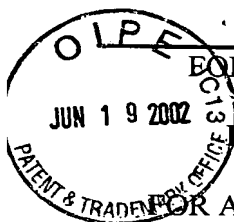
  
Signature: Colleen E. Doherty

FORM PTO-1449 (MODIFIED)

ATTORNEY DOCKET NO.

SERIAL NO.

JUN 19 2002



LIST OF PATENTS AND  
PUBLICATIONS  
FOR APPLICANTS INFORMATION  
DISCLOSURE STATEMENT

SP01-330

10/086,238

APPLICANT Bowden et al.

FILING DATE February 27, 2002

GROUP: 1731

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REFERENCE DESIGNATION

U.S. PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Name	Class	Sub-Class	Filing Date if Approp.
	AA	2,326,058	8/3/43	Nordberg	100	52	
	AB	4,501,602	2/26/85	Miller et al.	65	18.2	
	AC	5,043,002	8/27/91	Dobbins et al.	65	3.12	
	AD	5,152,819	10/6/92	Blackwell et al.	65	3.12	
	AE	5,154,744	10/13/92	Blackwell et al.	65	3.12	
	AF	5,686,728	11/11/97	Shafer	250	492.2	
	AG	5,970,751	10/26/99	Maxon et al.	65	414	
	AH	6,013,399	1/11/00	Nguyen	430	5	
	AI	6,299,318	10/9/01	Braat	359	856	

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Sub-Class	Translation Yes No
	AJ	WO 01/07967 *	2/1/01	PCT	G03C	5/00	X
	AK	WO 01/08163 *	2/1/01	PCT	G21K	5/00	X
	AL	WO 01/75522 *	10/11/01	PCT	G03F	1/14	X
	AM	WO 00/48775 *	8/24/00	PCT	B23B		X
	AN	WO 02/32622 *	4/25/02	PCT	B24B	7/24	X
	AO	WO 02/26647 *	4/4/02	PCT	C03B	37/016	X
	AP	WO 02/32616 *	4/25/02	PCT	B23P	13/04	
	AQ	EP 0 903 605A2	3/24/99	EPO	G02B	13/14	X
	AR	EP 1 106 582A2	6/13/01	EPO	C03B	19/10	X

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OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)

A1	P. Shultz & H. Smith, Ultra-Low-Expansion Glasses and Their Structure in the SiO <sub>2</sub> -TiO <sub>2</sub> System, Amorphous Materials, papers presented to the Third International Conference on the Physics of Non-Crystalline Solids, held at Sheffield University, September 1970
A2	George H. Beall, Industrial Applications of Silica, Reviews in Mineralogy, Vol. 29 (Silica), (1994), 469-505.
A3	Charles Gwyn et al., Extreme Ultraviolet Lithography, November 1999, 97-141.
A4	EUV Lithography NGL Technology Review, June 9, 1999, Chicago, Illinois
A5	Charles Gwyn et al., Extreme Ultraviolet Lithography, 1-6.
A6	William M. Tong et al., Substrates Requirements For Extreme Ultraviolet Lithography, Information Science & Technology, Lawrence Livermore National Laboratory, December 1999.
A7	O.V. Mazurin et al., Crystallization of Silica and Titanium Oxide-Silica Corning Glasses (Codes 7940 & 7971), Journal of Non-Crystalline Solids 18, (1975) 1-9.
A8	ISIMOTO CO. LTD., Purity and Chemical Reactivity, <a href="http://www.isimoto.com/isimoto/english/feature1.html">http://www.isimoto.com/isimoto/english/feature1.html</a> , 1-3, 5/17/99
A9	ISIMOTO CO. LTD., Product Information, <a href="http://www.isimoto.com/isimoto/english/product_info.html">http://www.isimoto.com/isimoto/english/product_info.html</a> , 1-4, 5/17/99
A10	Rapid Prototyping, <a href="http://mtiac.iitri.org/pubs/rp/rp1.htm">http://mtiac.iitri.org/pubs/rp/rp1.htm</a>
A11	Products: SLS (R) Systems – Introduction, Vanguard™ and Vanguard™ HS, <a href="http://www.3dsystems.com/products/slssystems/vanguard/index.asp?promo=">http://www.3dsystems.com/products/slssystems/vanguard/index.asp?promo=</a>
A12	Corning, Semiconductor Materials ULE Zero Expansion Glass, <a href="http://www.corning.com/semiconductormaterials/products_services/ule.asp">http://www.corning.com/semiconductormaterials/products_services/ule.asp</a>
A13	Richard H. Stulen et al., Extreme Ultraviolet Lithography, IEEE Journal of Quantum Electronics, Vol. 35, No. 5, May 1999, 694-699.

EXAMINER:

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